(12) INTERNATIONAL APPLICATION PUBLISHED UNDER THE PATENT COOPERATION TREATY (PCT)

(19) World Intellectual Property Organization
International Bureau

(43) International Publication Date
10 January 2002 (10.01.2002)

PCT

(10) International Publication Number
WO 02/002276 A3

(51) International Patent Classification[7]: B24B 37/04, 41/047, 47/10

(21) International Application Number: PCT/US01/41232

(22) International Filing Date: 29 June 2001 (29.06.2001)

(25) Filing Language: English

(26) Publication Language: English

(30) Priority Data:
60/215,666 1 July 2000 (01.07.2000) US

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(81) Designated States *(national)*: AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EE, ES, FI, GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS, JP, KE, KG, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV, MA, MD, MG, MK, MN, MW, MX, MZ, NO, NZ, PL, PT, RO, RU, SD, SE, SG, SI, SK, SL, TJ, TM, TR, TT, TZ, UA, UG, US, UZ, VN, YU, ZA, ZW.

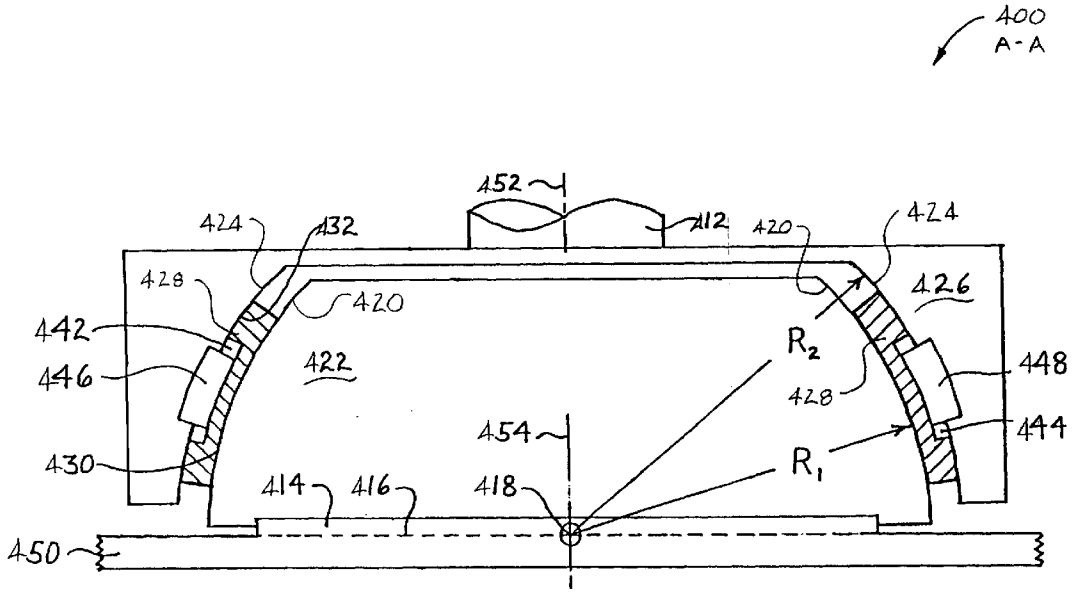
(84) Designated States *(regional)*: ARIPO patent (GH, GM, KE, LS, MW, MZ, SD, SL, SZ, TZ, UG, ZW), Eurasian patent (AM, AZ, BY, KG, KZ, MD, RU, TJ, TM), European patent (AT, BE, CH, CY, DE, DK, ES, FI, FR, GB, GR, IE, IT, LU, MC, NL, PT, SE, TR), OAPI patent (BF, BJ, CF, CG, CI, CM, GA, GN, GW, ML, MR, NE, SN, TD, TG).

**Published:**
— *with international search report*

(88) Date of publication of the international search report:
25 September 2003

*[Continued on next page]*

(54) Title: PROJECTED GIMBAL POINT DRIVE




(57) Abstract: A projected gimbal point drive system is disclosed. The projected gimbal point drive system includes a spindle (412) capable of apply a torque, and having a concave spherical surface formed on its lower portion. Further included is a wafer carrier disposed partially within the lower portion of the spindle (412). The wafer carrier (422) has a convex spherical surface (420) formed on a surface opposite the concave spherical surface (424) of the spindle. In addition, a drive cup is included that is disposed between the spindle and the wafer carrier. The drive cup (428) has a concave inner surface (430) and a convex outer surface (432), and allows the wafer carrier (422) to be tilted about a predefined gimbal point (418). In this manner, torque can be applied without affecting the gimbal action.

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